

FORM PTO-1449	DEC 27 2002	Attorney Docket Number	58027-011100
<b>INFORMATION DISCLOSURE STATEMENT BY APPLICANT</b>  (use as many sheets as necessary)		Application Number	10/060,737
		Filing Date	January 30, 2002
		Applicant(s)	Po-Hao Adam Huang et al.
		Group Art Unit	3743-1764
		Examiner Name	To Be Determined

U.S. PATENT DOCUMENTS						
EXAMINER INITIALS	DOCUMENT NUMBER	ISSUE DATE	PATENTEE	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
JAL	5,595,712 A	01-21-1997	Harbster et al.	422	129	
JAL	5,811,062 A	09-22-1998	Wegens et al.	422	129	
JAL	6,193,501 B1	02-27-2001	Masel et al.	431	170	

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FOREIGN PATENT DOCUMENTS							
EXAMINER INITIALS	DOCUMENT NUMBER	PUBLICATION DATE	COUNTRY OR PATENT OFFICE	CLASS	SUBCLASS	TRANSLATION	
						YES	NO

OTHER DOCUMENTS	
EXAMINER INITIALS	Include name of the author (in CAPITAL LETTERS), title of the article, title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.
JAL	International Search Report dated 13 December 2002

EXAMINER SIGNATURE	<i>[Signature]</i>	DATE CONSIDERED	2-19-2003
EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.			

Patent and Trademark Office; U.S. DEPARTMENT OF COMMERCE

**FORM 1449\***

INFORMATION DISCLOSURE STATEMENT  
IN AN APPLICATION  
(Use several sheets if necessary)

Docket Number:

510015-253

Application Number:

10/060,737

**Applicant:** Huang et al.

Filing Date: January 30, 2002

Group Art Unit: ~~2812~~ 1764

## U.S. PATENT DOCUMENTS

[illegible]

## FOREIGN PATENT DOCUMENTS

	DOCUMENT NO.	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
						YES	NO
						RECEIVED	
						SEP 18 2002	
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**OTHER DOCUMENTS** (Including Author, Title, Date, Pertinent Pages, Etc.)

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JAL	——	Y.C. Tai, "A High Performance MEMS Thin-Film Teflon Electret Microphone," 1999 International Conference on Solid-State Sensors and Actuators (Transducers '99), Sendai, Japan, Jun.(1999).
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JAL	——	Wegeng, Robert S., et al. "Micro Chemical System Development Progress at the Pacific Northwest National Laboratory," Pacific Northwest National Laboratory, Washington, 1997.
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JAL	——	Suzuki, Hiroaki, et al., "A Magnetic Force Driven Chaotic Micro-Mixer," Proceedings, MEMS, Las Vegas, 2002.
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JAL	——	Liu, Robin H., et al, "Passive Mixing in a Three-Dimensional Serpentine Microchannel," Journal of Microelectromechanical Systems, Vol. 9, No. 2, June 2000

**EXAMINER**

DATE CONSIDERED 2-19-2003

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